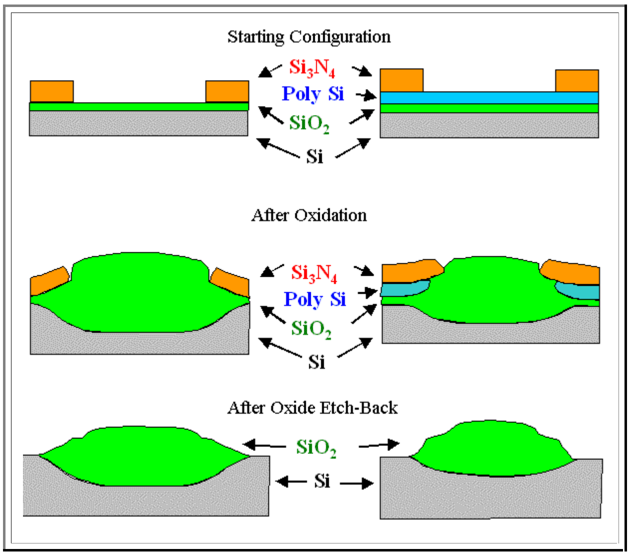
# LOCOS with Sacrificial Poly-Silicon

Illustration

- Here is a comparison of the **LOCOS** process with and without some sacrificial poly-**Si:**



  - Provided, some of the oxide is removed by an "etch-back" process, the lateral extension can be kept somewhat smaller than in the conventional case.
- While this makes things quite complicated, the final versions of the **LOCOS** process were even more complicated.